

FILED VIA EFS WEB

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE****PATENT**

Applicants:	Nishio, et al.	Docket No.:	49288.2800
Serial No.:	10/595,201	Examiner:	Laura M. Lee
Filed:	January 2, 2007	Group Art Unit:	3724
Title:	SUBSTRATE DICING SYSTEM, SUBSTRATE MANUFACTURING APPARATUS, AND SUBSTRATE DICING METHOD	Confirmation No.:	4462

**AMENDMENT AND REPLY**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Commissioner:

In reply to the Office Action dated April 14, 2010, of which this Reply is filed within three months, please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.

DO NOT ENTER: /L.L./

07/14/2010